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Sheet 1 of 2

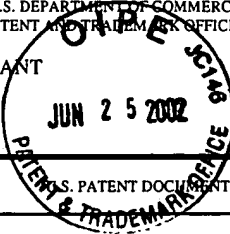
Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1965		SERIAL NO. Unknown	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Jigish D. Trivedi et al.			
				FILING DATE Filed herewith		GROUP Unknown	
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*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
DLO	AA	5,254,489	10/19/93	Nakata	437	40	
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	AC	5,620,908	4/15/97	Inoh et al.	438	207	
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	AJ	4,651,406	03/1987	Shimizu et al.	29	571	
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						Yes	No
	AL	6302813 A	04/1993	Japan			
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DLO	AS		Kuroi et al., "The Effects of Nitrogen Implantation Into P + Poly-Silicon Gate on Gate Oxide Properties", 1994 Symposium on VLSI Technology Digest of Technical Papers, pp. 107-108.				
DLO	AT		Doyle et al., "Simultaneous Growth of Different Thickness Gate Oxides in Silicon CMOS Processing", IEEE Electron Device Letters, Vol. 16, No. 7.				
EXAMINER Douglas W. Owens			DATE CONSIDERED 7/4/02				
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

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U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
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DKJ	AB	6,165,846	12/2000	Carns et al.	438	264	
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		Document Number	Date	Country	Class	Subclass	Translation
							Yes    No
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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1965		SERIAL NO. 10087,416		
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Jigish D. Trivedi et al.				
				FILING DATE Filed herewith		GROUP 2811		
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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
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							Yes	No
	AL	326352-A	2001	Japan (Abstract provided w/untranslated patent)				
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LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)								
				APPLICANT Jigish D. Trivedi et al.				
				FILING DATE February 27, 2002	GROUP 2811			
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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
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EXAMINER <i>Douglas W. Owens</i>				DATE CONSIDERED <i>7/11/02</i>				
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